

U.S. Department of Commerce, Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)					Application No.:		Unknown	
					Filing Date:		Unknown	
					First Named Inventor:		Jaime Poris	
					Group Art Unit:		Unknown	
					Examiner Name:		Unknown	
					Confirmation No.:		Unknown	
Copies of References located in Parent Application Serial No. 09/724,813					Attorney Docket No.:		NAN042-1D US	
U.S. Patent Documents								
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
ML	1.	5,314,843	5/24/1994	Yu et al	437	225		
ML	2.	5,348,002	9/20/1994	Caro	128	633		
ML	3.	5,555,471	10-Sep-96	Xu et al.	356	357		
ML	4.	5,784,163	7/21/1998	Lu et al	356	351		
ML	5.	5,872,629	2/16/1999	Colvard	356	349		
ML	6.	5,874,318	2/23/1999	Baker et al	438	8		
ML	7.	5,914,782	22-Jun-99	Sugiyama	356	351		
ML	8.	5,953,115	14-Sep-99	Landers et al.	356	237		
ML	9.	5,983,167	11/9/1999	Ebisawa	702	167		
ML	10.	6,238,592	29-May-01	Hardy et al	252	79.1		
ML	11.	6,340,602	1/22/2002	Johnson et al.	438	7		
ML	12.	6,392,749	21-May-02	Meeks et al.	356	381		
ML	13.	6,392,752	5/21/2002	Johnson	356	511		
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No.
ML	14.	EL 0 831 295 A1	3/25/1998	EP				
ML	15.	EP 0 982 774 A2	3/1/2000	EP				
ML	16.	WO 00/54325	9/14/2000	PCT				
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
ML	17.	Azzam, R. "Ellipsometry and Polarized Light" Elsevier Science B.V. (1977, 1987); Pages 282-287						
Examiner <i>ML</i>		Date Considered <i>February 17, 2004</i>						
*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)			
18.	W	Fujiwara, H et al., "Dept-profiles in compositionally-graded amorphous silicon alloy thin films analyzed by real time spectroscopic ellipsometry" <i>Elsevier Science S.A.</i> pages 474-478.(1998)	
19.	W	Heavens, O.S. "Optical Properties of Thin Film Solids" <i>Dover Publications, Inc.</i> (1991), pages 62-73	
20.	W	Jennewin, H. et al., "Interferometrical Profilometry at Surfaces with Varying Materials" <i>SPIE Vol. 3677</i> 1999), pages 1009-1016	
21.	W	Kildemo, M. et al., "Measurement of the absorption edge of thick transparent substrates using the incoherent reflection model and spectroscopic UV - visible - near IR ellipsometry" <i>Elsevier Science S.A.</i> pages 108-113 (1998)	
22.	W	Kim, Gee-Hong et al., "White light scanning interferometry for thickness measurement of thin film layers" <i>SPIE Vol. 3783</i> (1999), pages 239-246	
23.	W	Makosch, G., "LASSI - a scanning differential ac interferometer for surface profile and roughness measurement" <i>SPIE vol. 1009</i> , (1988); Pages 244-253	
24.	W	Makosch, G. et al., "Surface profiling by electro-optical phase measurements" <i>SPIE Vol. 316</i> (1981), pages 42-53	
25.	W	"Numerical Recipes, The Art of Scientific Computing" by Press, Flannery, Teukolsky and Vetterling, published by Cambridge University Press 1988, 3.2 Rational Function Interpolation and Extrapolation, Pages 83-85... (1988)	
Examiner	M. D. C. [Signature]		Date Considered February 17, 2004
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